

Notice of References Cited	Application/Control No. 10/604,096	Applicant(s)/Patent Under Reexamination ABADEER ET AL.	
	Examiner Tuan H. Nguyen	Art Unit 2813	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-5,597,586	01-1997	Wilson et al.	425/67
*	C	US-5,654,218	08-1997	Lee, Bong Jae	438/301
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*	E	US-5,210,435	05-1993	Roth et al.	257/344
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Chen et al., "'Self-Aligned Silicided Inverse-T Gate LDD Devices For Sub-Half Micron CMOS Technology", IEDM, 1990. Technical Digest., International, 9-12 Dec. 19, pages 829-832.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.